

03500.015382

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKAHARU KONDO ET AL

Application No.: 09/866,665

Filed: May 30, 2001

For: SILICON-TYPE THIN FILM
FORMATION PROCESS, SILICON-
TYPE THIN FILM, AND
PHOTOVOLTAIC DEVICE

Examiner: B.L. Mutschler

Art Unit: 1753

February 26, 2003

9/8
W.M.
2/28/03FAX RECEIVED
FEB 28 2003
GROUP 1700Commissioner for Patents
BOX AF
Washington, D.C. 20231RESPONSE TO OFFICE ACTION AND REQUEST FOR RECONSIDERATION

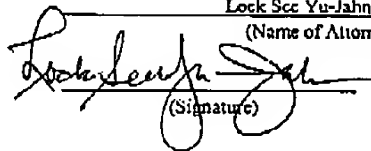
Sir:

In response to the Office Action dated November 26, 2002, the Examiner is
respectfully requested to consider to following:

I hereby certify that this correspondence is being facsimile transmitted to the
United States Patent and Trademark Office (Fax No. 703-872-9311) on

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Lock See Yu-Jahnes (Reg. No. 38,667)
(Name of Attorney for Applicants)


(Signature)

February 26, 2003
(Date of Signature)